

CLAIMS SET AS AMENDED

1. (Currently Amended) A method of forming a liquid crystal layer on a substrate having a sealed pattern, comprising:

preparing a liquid crystal material in a projecting portion;

applying a vibration and pressure to the projecting portion so as to emit the liquid crystal material from the projecting portion;

moving the substrate in one direction; ~~and~~

depositing the emitted liquid crystal material uniformly onto the substrate during the movement of the substrate in the one direction-; and

adjusting an on-off of a voltage according to a position of the moving substrate.

2. (Original) The method according to claim 1, wherein the projecting portion has a nozzle plate containing a plurality of orifices, said nozzle plate adjusting the applied pressure for emitting the liquid crystal material, said liquid crystal material being emitted through the plurality of orifices.

3. (Cancelled)

4. (Original) The method according to claim 1, wherein the liquid crystal material is emitted and deposited in a vacuum chamber.

5. (Original) The method according to claim 1, wherein the vibration is generated by a voltage applied to a resonator.

6. (Original) The method according to claim 5, wherein the generated vibration is transmitted to the projecting portion through a resonating plate.

7. (Original) The method according to claim 1, wherein the substrate has a black matrix under the sealed pattern.

8. (Original) The method according to claim 7, wherein the liquid crystal material start and stop is deposited on the black matrix.

9. (Currently Amended) An apparatus for forming a liquid crystal layer on a substrate having a seal pattern, comprising:

a projecting portion for emitting a liquid crystal material;

a resonator for generating a vibration;

a resonating plate located between the resonator and the projecting portion for transmitting the vibration to the projecting portion; and

a stage for moving the substrate in one direction during emitting of the liquid crystal material from the projecting portion uniformly onto the substrate, wherein an on-off of a voltage applied to said apparatus is adjusted according to a position of the moving substrate.

10. (Original) The apparatus according to claim 9, wherein the projecting portion has a nozzle plate containing a plurality of orifices, the nozzle plate adjusting the applied pressure for emitting the liquid crystal material, the liquid crystal material being emitted through said plurality of orifices.

11. (Cancelled)

12. (Previously Presented) The apparatus according to claim 9, wherein means are provided for moving the stage.

13. (Original) The apparatus according to claim 9, further comprising a vacuum chamber for encompassing the projecting portion, the resonator and the resonating plate.

14. (Original) The method according to claim 9, wherein voltage means are provided for generating vibration in the resonator.